

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No.10/097,025
Priority Filing DateMarch 11, 2002
InventorTrung Tri Doan et al.
AssigneeMicron Technology, Inc.
Priority Group Art Unit1763
Priority ExaminerKarla A. Moore
Attorney Docket No.MI22-2471
Title: Atomic Layer Deposition Apparatus and Method

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a divisional/continuation application of co-pending application Serial No. 10/097,025, filed March 11, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated 12-17-03

By: 
Mark S. Matkin
Reg. No. 32,268

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		ATTY. DOCKET NO. <u>MI22-2471</u>		SERIAL NO. <u>PRIORITY 10/097,025</u>			
		APPLICANT: <u>Micron Technology, Inc.</u>					
		FILING DATE <u>PRIORITY March 11, 2002</u>		GROUP <u>PRIORITY 1763</u>			
		U.S. PATENT DOCUMENTS					
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	4,793,283	12/1988	Sarkozy	118	725	
	AB	5,000,225	03/1991	Murdoch	137	625.46	
	AC	5,242,539	09/1993	Kumihashi et al.	216	67	
	AD	5,286,296	02/1994	Sato et al.	118	719	
	AE	5,607,510	03/1997	Makino et al.	118	723	
	AF	5,746,581	05/1998	Okumura et al.	417	2	
	AG	6,214,120	04/2001	Kim	118	719	
	AH	6,306,247	10/2001	Lin	156	345.29	
	AI	6,316,045	11/2001	Bernard et al.	427	8	
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes
	AJ	JP 62192582 A	08/1987	Japan			No
	AK	JP 02220367 A	09/1990	Japan			
	AL	JP 06005520 A	01/1994	Japan			
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AM						
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EXAMINER		DATE CONSIDERED					
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	AJ						

FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
	AJ	JP 2001220677 A	08/2001	Japan			Yes
	AK						No
	AL						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
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